Special Issue

New Trends in Semiconductor and Nanophotonic Devices and Their Applications

Message from the Guest Editors

Semiconductor and nanophotonic devices are attracting growing attention from the academia and industry. Their applications have started several trends in different fields including physics, engineering and materials. Some topics such as 2D material devices and perovskites are already carefully discussed and are about to be applied in industries but may still have more surprising new trends to be discovered. Some topics such as metamaterial and quantum optics are new topics to be explored. There are many methods to research devices or material properties such as Raman spectroscopy and photoluminescence. Temperature, excitation laser power, and excitation laser wavelength may all have an impact on the spectra. This Special Issue focuses on the new trends in semiconductor and nanophotonic devices and their applications. Any research paper that involves the processing of the nanophotonic device, analysis of material, and modelling of phenomena is welcomed. The novelty of the idea is a crucial characteristic that we are looking for.

Guest Editors

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